



Attorney's Docket No. 42390P5778D

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Krishna Seshan et al.

Application No. 10/013,103

Filed: November 6, 2001

For: **Semiconductor Passivation Deposition Process
for Interfacial Adhesion**

Examiner: Lewis, Monica

Art Unit: 2822

Mail Stop RCE
Commissioner for Patents
P. O. 1450
Alexandria, VA 22313-1450

Sir:

In connection with the filing of the Request for Continuing Examination, Applicant respectfully requests entry of the following amendment set forth below.